

UNITED STATES PATENT AND TRADEMARK OFFICE



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PPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO
09/857,453	09/05/2001	Ya-Chin King	015057-09162	4772
7:	590 10/23/2002			
Henry K Woodward			EXAMINER	
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,			2826	

Please find below and/or attached an Office communication concerning this application or proceeding.

Art Unit: 2826

DETAILED ACTION

Election/Restrictions

Applicant's election of device in Paper No. 7 is acknowledged. Because applicant did not distinctly and specifically point out the supposed errors in the restriction requirement, the election has been treated as an election without traverse (MPEP § 818.03(a)).

Claim Rejections - 35 USC § 103

The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:

(a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as a whole would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negatived by the manner in which the invention was made.

Claims 16-20 are rejected under 35 U.S.C. 103(a) as being unpatentable over U.S. Patent No. 6,054,374. Gardner et al. in view of U.S. Patent No. 5,930,620 Wristers et al.

1. Referring to claim 16, a semiconductor device having a gate oxide of multiple thickness, the semiconductor device comprising: a first gate oxide region having a first thickness, (Gardner et al. Col. 7 Lines 46-47 & Wristers et al. Col. 6 Lines 29-30), and a second gate oxide region having a second thickness, (Gardner et al. Col. 7 Lines 48-49 & Wristers et al. Col. 6 Lines 31-32), the second gate oxide region being oxygen-implanted oxide, (Wristers et al. Col. 6 Lines 26-

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27), the second thickness being greater than the first thickness, (Gardner et al. Col. 7 Lines 56-61 & Wristers et al. Col. 6 Lines 33-36).

Gardner et al. teaches all of the claimed matter in claim 1 except for the oxygen implants which is used for enhancing the growth of oxide, but a nitride implant is taught which is used to inhibit the growth of the oxide. Wristers et al. teaches using an oxygen implant to accelerate the growth of an oxide. It would have been obvious to combine the teachings of Gardner et al. with the teachings of Wristers et al. because it is well known in the art that impurities, such as nitrogen, that are added to an oxide reduces the insulating properties and thermal tolerances causing a lower breakdown voltage of the oxide.

2. Referring to claim 17, a semiconductor device having a gate oxide of multiple thickness, wherein the first thickness is less than about 30Å, (Gardner et al. Col. 7 Lines 55-56).

Note that the specification contains no disclosure of either the critical nature of the claimed dimensions or any unexpected results arising therefrom. Where patentability is said to be based upon particular chosen dimensions or upon another variable recited in a claim, the Applicant must show that the chosen dimensions are critical. <u>In re Woodruff</u>, 919 F.2d 1575, 1578, 16 USPQ2d 1934, 1936 (Fed. Cir. 1990).

3. Referring to claim 18, a semiconductor device having a gate oxide of multiple thickness, wherein the first thickness is less than the second by less than about 20Å, (Gardner et al. Col. 7 Lines 56-61).

Note that the specification contains no disclosure of either the critical nature of the claimed dimensions or any unexpected results arising therefrom. Where patentability is said to be based upon particular chosen dimensions or upon another variable recited in a claim, the Applicant must show that the chosen dimensions are critical. <u>In re Woodruff</u>, 919 F.2d 1575, 1578, 16 USPQ2d 1934, 1936 (Fed. Cir. 1990).

4. Referring to claim 19, a semiconductor device having a gate oxide of multiple thickness, wherein the first gate oxide region is non-implanted oxide, (Col. 7 Lines 22-26).

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5. Referring to claim 20, a semiconductor device having a gate oxide of multiple thickness,

wherein the first gate oxide, (Gardner et al. Col. 7 Lines 46-47 & Wristers et al. Col. 6 Lines 29-

30), is oxygen implanted oxide, the implanted oxygen concentration being less than the

implanted oxygen concentration, (Gardner et al. Col. 7 Lines 56-61), of the second gate oxide

region, (Gardner et al. Col. 7 Lines 48-49 & Wristers et al. Col. 6 Lines 31-32).

Conclusion

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Victor A Mandala Jr. whose telephone number is (703) 308-6560.

The examiner can normally be reached on Monday through Thursday from 8am till 6pm..

If attempts to reach the examiner by telephone are unsuccessful, the examiner's

supervisor, Nathan Flynn can be reached on (703) 308-6601. The fax phone numbers for the

organization where this application or proceeding is assigned are (703) 308-7722 for regular

communications and (703) 308-7724 for After Final communications.

Any inquiry of a general nature or relating to the status of this application or proceeding

should be directed to the receptionist whose telephone number is (703) 308-0956.

VAMJ

October 17, 2002

NATHAN I PLYNN

SUPERVISORY PATENT EXAMINER

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